

November 2, 2006

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450
U.S.A.

Re: Correction of International Application Number in an
Existing Utility Patent Application

Application No.: 10/598,933

Confirmation No.: 2213

Filing date:

Believed to be September 14, 2006

Title:

SEMICONDUCTOR WAFER INSPECTION

DEVICE AND METHOD

Application Type:

U.S. National Stage under 35 USC 371

Atty. Docket No:

PA214WP002

First Inventor:

Fumi NABESHIMA

Assignee:

Komatsu Electronic Metals Co., Ltd.

Sir:

With regard to the captioned patent application: An error is noted in the International Application Number therefor.

The correct International Application Number is PCT/JP05/07120.

It is respectfully requested that the Office update its records to reflect the correct International Application Number provided herein.

Respectfully submitted,



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JF/so